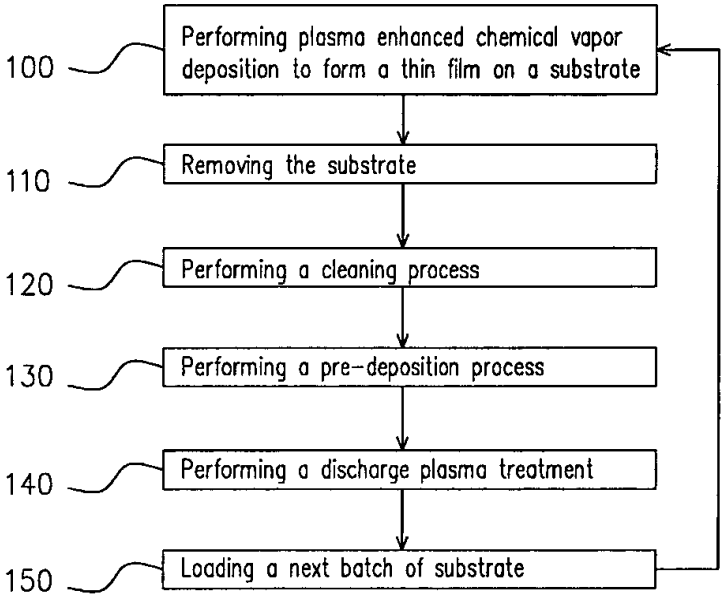
100
Performing plasma enhanced chemical vapor deposition to form a thin film on a substrate
110
Removing the substrate
120
Performing a cleaning process
130
Performing a pre-deposition process
140
Performing a discharge plasma treatment
150
Loading a next batch of substrate

FIG. 1